

Docket No.: 58799-034

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PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Yoichi OSE, et al.

Serial No.: 09/768,356

Group Art Unit: 2881

Filed: January 25, 2001

Examiner:

For: SCANNING ELECTRON MICROSCOPE

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Supplemental Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

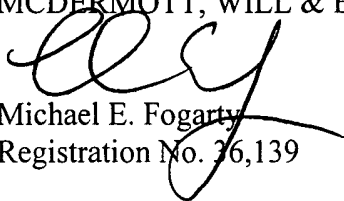
The Japanese Patent Laid-Open No. HEI 9-171791 is the priority application of United States Patent No. 5,872,358 that was listed in the Information Disclosure Statement filed on January 25, 2001.

09/768,356

The relevance of each non-English language reference, if any, is discussed in the present specification.

Respectfully submitted,

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